



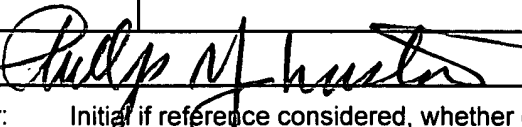
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U.S. PATENT DOCUMENTS							
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FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Sub Class	Translation Yes or No		

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
	KOIKE, T. et al., "Investigation of Scanning Electron Microscope Overlay Metrology", Japanese Journal Of Applied Physics, Vol. 38, pp. 7159-7163, (1999).
	URA, K., "Contrast Mechanism of Negatively Charged Insulators in Scanning Electron Microscope", Journal of Electron Microscopy, Vol. 47, No. 2, pp. 143-147, (1998).
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